# Minimizing Leakage Power in CMOS: Technology Issues

Centre SI Summer School on Nanoelectronic Circuits and Tools

Massoud Pedram Dept. of Electrical Engineering University of Southern California

July 15, 2008

# Physical Structure of a Long N-Channel Enhancement-Type MOSFET



• Threshold voltage,  $V_T$ , is defined as the voltage at which an MOS transistor begins to conduct. For voltages less than  $V_T$ , the channel is cut off.

n-channel enhancement MOS



#### Threshold Voltage of an nMOS Transistor

For  $V_{SB}=0$ , the threshold voltage,  $V_{T0}$ , is defined as the gate potential  $V_G$  at which the surface potential  $\phi_s$  changes by  $2\phi_F$ , i.e., the surface becomes strongly inverted.

Flat band voltage Ideal threshold voltage  $V_{T0} = \left( \Phi_{GC} - \frac{qN_{OX}}{C_{OX}} \right) + \left( -2\phi_F - \frac{Q_{B0}}{C_{OX}} \right) + \frac{qN_I}{C_{OX}}$ Channel-implant induced shift

 $\Phi_{\mathsf{GC}} \Rightarrow$  The work function difference between the gate and the channel

qN<sub>OX</sub> ⇒ Positive charge density at the gate Si-oxide interface due to impurities and lattice imperfections at the interface (Sign is always positive)

- $\phi_{\mathsf{F}} \quad \Rightarrow \text{ The substrate Fermi potential}$
- $Q_{BO} \Rightarrow$  Depletion charge density at surface inversion
- qN<sub>I</sub> ⇒ Additional channel implant density (Sign is positive for p-type and negative for n-type implant)

nMOS transistor:  $Q_{BO} = -\sqrt{2qN_A\varepsilon_{Si} | -2\phi_F |}$ 

pMOS transistor:  $Q_{BO} = \sqrt{2qN_D\varepsilon_{S_i} | -2\phi_F |}$ 

#### Threshold Voltage (Cont'd)

 $\Phi_{GC} = \phi_F - \phi_{F(gate)}$   $\phi_{F(gate)} = \begin{cases} 0.55V & \text{for heavily doped n-type polysilicon gate (edge of conduction band)} \\ -0.55V & \text{for heavily doped p-type polysilicon gate (edge of valence band)} \\ \phi_M & \text{for metal gate} \end{cases}$ 

$$\varepsilon_{ox} = 0.34 \times 10^{-12} Fcm^{-1}, \ \varepsilon_{si} = 1.06 \times 10^{-12} Fcm^{-1}$$

$$C_{OX} = \frac{\mathcal{E}_{OX}}{t_{OX}}$$

Threshold voltage determinants:

- Gate conductor materials
- Gate oxide material & thickness
- Substrate doping
- Channel Ion Implantation
  - p-type (n-type) impurities,  $V_T$  is made more positive (negative)
- Impurities in Si-oxide interface, Qox
- Source-bulk voltage,  $\mathrm{V}_{\mathrm{SB}}$
- Temperature, T

#### Threshold Voltage (Cont'd)



# Cross-sectional View of an nMOS Transistor when $V_G > V_T$



#### NMOS $I_D$ - $V_{DS}$ and $I_D$ - $V_{GS}$ Curves



nMOS transistor, with  $k_n = k_n \frac{W}{L} = \mu_n C_{ox} \frac{W}{L}$ •

Gate Voltage

$$I_{D}(cutoff) = 0 \quad V_{GS} < V_{T}$$

$$I_{D}(lin) = \frac{k_{n}}{2} \left( 2 \left( V_{GS} - V_{T}(V_{SB}) \right) V_{DS} - V_{DS}^{2} \right) \quad V_{GS} \ge V_{T}, V_{DS} < V_{GS} - V_{T}$$

$$I_{D}(sat) = \frac{k_{n}}{2} \left( V_{GS} - V_{T}(V_{SB}) \right)^{2} \left( 1 + \lambda V_{DS} \right) \quad V_{GS} \ge V_{T}, V_{DS} \ge V_{GS} - V_{T}$$

#### Short-Channel Effects

- A MOS transistor is called a short-channel device if its channel length is on the same order of magnitude as the depletion region thickness of the source and drain junctions
- The short-channel effects are attributed to two physical phenomena:
  - 1. Limitation on the electron drift characteristics in the channel
  - 2. Reduction of the threshold voltage due to shortening of the channel length



# Short-Channel Effect on Electron Drift Characteristics

- In short-channel MOS transistor, the carrier velocity in the channel is also a function of the vertical component of the electric field,  $E_x$
- Since the vertical field influences the scattering of the carriers in the surface, the surface mobility is reduced with respect to the bulk mobility
- The surface electron mobility can be expressed as follows:

$$\mu_n(eff) = \frac{\mu_{n0}}{1 + \zeta \left( V_{GS} - V_T \right)}$$

where  $\mu_{n0}$  is the low-field surface mobility and  $\zeta$  is an empirical factor

### Alpha-Power Current Equation for Short-Channel Devices

• In some textbooks, we see the following simplified equation for shortchannel MOSFET current in saturation:

$$I_D(sat) = W v_{d,sat} C_{ox} (V_{GS} - V_T - V_{DSAT})$$

• More often, we adopt the alpha-power current equation for short-channel MOSFETs, which is as follows:

$$I_D(sat) = \frac{k_{n(p)}}{2} \left( V_{GS} - V_T \right)^{\alpha} \quad where \quad 1 < \alpha \le 2$$

For a 60nm bulk CMOS process, $\alpha = 1.45$ .



Plot of actual drain current vs. alpha-power current predictions for a 60nm bulk CMOS process

#### Example

- Suppose you were to design an NMOS transistor in a 0.18mm CMOS process. The transistor width is 0.72 $\mu$ m, and length is 0.18 $\mu$ m. The manufacturing process could result in a 25% variation in the threshold voltage, a 20% variation in the oxide thickness, and a 0.1 $\mu$ m variation in the width and in the length for the actual device that is fabricated. Assume that V<sub>GS</sub> = V<sub>DS</sub> = 1.8V and that the threshold voltage is 0.5V. What is the ratio of the maximum value of the drain current to the minimum value of the drain current that could flow through the fabricated device when it is in saturation?
- Solution: We use the alpha power saturated current equation with  $\alpha$ =1.4. For max drain current, t<sub>ox1</sub>=0.8t<sub>ox</sub>, W<sub>1</sub>=W+0.1µm=0.82µm, L<sub>1</sub>=L-0.1µm=0.08µm V<sub>th1</sub>=0.75V<sub>th</sub>=0.375, V<sub>th2</sub>=1.25V<sub>th</sub>=0.625

For min drain current,  $t_{ox2}=1.2t_{ox}$ ,  $W_2=W-0.1\mu m = 0.62\mu m$ ,  $L_2=L+0.1\mu m = 0.28\mu m$ 

$$\frac{I_{d \max}}{I_{d \min}} = \frac{\frac{W_1}{t_{ox1}L_1} (V_{DD} - V_{th1})^{1.4}}{\frac{W_2}{t_{ox2}L_2} (V_{DD} - V_{th2})^{1.4}} = \frac{\frac{0.82}{0.8 \times 0.08} (1.8 - 0.375)^{1.4}}{\frac{0.62}{1.2 \times 0.28} (1.8 - 0.625)^{1.4}} = 9.1$$

# Short Channel Effect (SCE) and Drain Induced Barrier Lowering (DIBL)

• In short-channel MOS, there is a significant amount of depletion charge around the source and drain, and therefore, the long channel model overestimates the depletion charge that must be supported by the gate voltage

$$V_{T0}(short channel) = V_{T0} - \Delta V_{T0}$$

•  $\Delta V_{T0}$  is the threshold voltage reduction due to the short-channel effect:

$$\Delta V_{T0} = \frac{1}{C_{ox}} \sqrt{2q\varepsilon_{Si}N_A \left| 2\phi_F \right|} \frac{x_j}{L} \left[ \frac{1}{2} \left( \sqrt{1 + \frac{2x_{dS}}{x_j}} + \sqrt{1 + \frac{2x_{dD}}{x_j}} \right) - 1 \right]$$

•  $V_T$  is also reduced due to the Drain Induced Barrier Lowering (DIBL)



DIBL effect on barrier height (higher  $V_{DS}$  causes  $V_T$  of a short channel transistor to decrease)

## Combined Effect of SCE and DIBL on Threshold Voltage

- Most noticeable in short-channel devices
  - Especially important in the subthreshold regime



### Subthreshold Current (I<sub>sub</sub>)

- If the drain-source voltage is above 0V, the potential barrier for the electrons in the channel decreases and we have current even though  $V_{GS} < V_{T0}$
- The channel current that flows under these conditions  $(V_{GS} \le V_{T0})$  is called the *sub-threshold current*:

$$I_D(sub) \equiv I_{sub} = \frac{W}{L} \mu_e(n-1)C_{ox} \mathcal{P}_T^2 e^{\frac{V_{GS} - V_T + \eta V_{DS}}{n\mathcal{P}_T}} \left(1 - e^{\frac{-V_{DS}}{\mathcal{P}_T}}\right) \propto e^{\frac{V_{GS} - V_T + \eta V_{DS}}{n\mathcal{P}_T}} = 10^{\frac{V_{GS} - V_T + \eta V_{DS}}{S}}$$

- The inverse subthreshold slope, S, is equal to the voltage required to increase I<sub>D</sub> by 10X, i.e.,  $S = \left(\frac{\partial(\log_{10} I_{sub})}{S}\right)^{-1} = ng_r \ln 10 = 2.3n^{\frac{k}{2}}$ 
  - If n = 1, S = 60 mV/dec at 300 K

$$= \left(\frac{\partial(\log_{10} I_{sub})}{\partial V_{GS}}\right)^{-1} = n\mathcal{G}_T \ln 10 = 2.3n\frac{kT}{q}$$

- We want S to be small to shut off the MOSFET quickly
- In well designed devices, S is 70 90 mV/dec at 300 K.

# Modeling the Off Current $(I_{off})$

- Note that  $n=1+\frac{C_{dep}+C_{it}}{C_{ax}}$
- Modulation of  $V_T$  in a short channel transistor
  - L ↓ ⇒  $V_T$  ↓: " $V_T$  Rolloff"
  - $V_{DS}$  ↑ ⇒  $V_T$  ↓:"Drain Induced Barrier Lowering"
  - $V_{SB}$  ↑ ⇒  $V_T$  ↑: "Body Effect"

• If 
$$V_{DS} = 0 \implies I_{sub} = 0$$

• long-channel device with 
$$V_{DS} > 3n \vartheta_T \implies I_{sub} = \frac{W}{I} \mu_e (n-1) C_{ox} \vartheta_T^2 e^{-n \vartheta_T}$$

• Now, we have: 
$$I_{off} \equiv I_{sub}(V_{GS}=0) = \frac{W}{L}\mu_e(n-1)C_{ox}\mathcal{G}_T^2 e^{\frac{-V_T}{n\mathcal{G}_T}}$$

- Key dependencies of the subthreshold slope:
  - $t_{ox} \downarrow \Rightarrow C_{ox} \uparrow \Rightarrow n \downarrow \Rightarrow \text{sharper subthreshold}$
  - $N_A \uparrow \Rightarrow C_{sth} \uparrow \Rightarrow n \uparrow \Rightarrow \text{ softer subthreshold}$
  - $V_{SB} \uparrow \Rightarrow C_{sth} \downarrow \Rightarrow n \downarrow \Rightarrow \text{sharper subthreshold}$
  - $T \uparrow \Rightarrow$  softer subthreshold

 $V_{GS} - V_T$ 

117

#### Subthreshold Swing

- $V_T \clubsuit, I_{off} \Upsilon$
- Subthreshold swing (S)  $\boldsymbol{\hat{\upsilon}}$  ,  $\boldsymbol{I}_{off}$   $\boldsymbol{\hat{\upsilon}}$
- S î with increased doping density, reduced gate length (draininduced barrier lowering)
- SOI is able to hold S = 60 mV/decade



### Gate Oxide Leakage

- At 15 Å the dielectric material will only have a bulk thickness of three atomic layers of silicon
  - Around this thickness, electrical leakage current through the dielectric becomes excessive and is expected to cause problems due to either high power dissipation or circuit reliability
- Gate oxide leakage current per unit length of the 65 nm nMOS FET (with  $t_{ox}$  of 15°A) is below 1 nA/um
  - This gate leakage current is well below the transistor  $I_{off}$  of about 30nA/um at a  $V_{DD}$  of 1V and the nMOS transistor  $I_D(sat)$  of 775uA/um (this value is 270uA/um for the pMOS transistor)





### Modern Si MOSFET Structure

- Silicided junctions
  - Minimizes junction parasitic resistances
- Lightly doped drain (LDD)
  - A.k.a. shallow junction extension
  - Reduces hot carrier effect by lowering horizontal electric field
  - Need to watch for performance degradation
- Packet Halo implant and super steep retrograde channel implant with LDD
  - Control short channel effects

• Suppresses punch-through M. Pedram USC/EE



## Modern Si MOSFET (Cont'd)

- Cu interconnect and low-k ILD
  - Improves VLSI interconnect performance
- High-k gate dielectric and metal gate
  - Example: replace SiO<sub>2</sub> (k=4) with Si<sub>3</sub>N<sub>4</sub> (k=8) or HfO<sub>2</sub> (k  $\approx$  25)
  - Reduces tunneling gate leakage current by increasing the effective oxide thickness
- Strained Si or strained SiGe
  - Enhances electron/hole mobility and increases saturation velocity
- Multi-gate devices
  - Example: Double-gate FinFET
  - Provides better gate control over the channel
- Improves the subthreshold swing  $_{\mbox{\scriptsize M. Pedram USC/EE}}$



Current Cu technology



#### **Constant-Field Scaling**

- This scaling option attempts • to preserve the magnitude of internal electric fields in the MOSFET, while the dimensions are scaled down by a factor of S
- The scaling factor for  $\bullet$ different parameters in this case is as follows:
  - 1. All dimensions, including those vertical to the surface, 1/S
  - Device voltages, 1/S 2.
  - 3. Concentration densities, S

Quantity	Before Scaling	After Scaling
Channel length	L	L'=L/S
Channel width	W	W'=W/S
Gate oxide thickness	t <sub>ox</sub>	$t_{ox} = t_{ox}/S$
Junction depth	Xj	x <sub>j</sub> '=x <sub>j</sub> /S
Power supply voltage	V <sub>DD</sub>	V <sub>DD</sub> '=V <sub>DD</sub> /S
Threshold voltage	V <sub>T0</sub>	$V_{T0}' = V_{T0}/S$
Doping densities	N <sub>A</sub> & N <sub>D</sub>	N <sub>A</sub> '=S.N <sub>A</sub>
		$N_D = S.N_D$





DOPING=  $\alpha N_{A}$ 

#### Full Scaling (Cont'd)

• For linear mode and saturation mode drain current we have:

$$I'_{D}(lin) = \frac{k'_{n}}{2} \Big[ 2 \Big( V'_{GS} - V'_{T} \Big) V'_{DS} - V'^{2}_{DS} \Big]$$
  
$$= \frac{Sk_{n}}{2} \frac{1}{S^{2}} \Big[ 2 \Big( V_{GS} - V_{T} \Big) V_{DS} - V^{2}_{DS} \Big] = \frac{I_{D}(lin)}{S}$$
  
$$I'_{D}(sat) = \frac{k'_{n}}{2} \Big( V'_{GS} - V'_{T} \Big)^{2} = \frac{Sk_{n}}{2} \frac{1}{S^{2}} \Big( V_{GS} - V_{T} \Big)^{2} = \frac{I_{D}(sat)}{S}$$

• For power dissipation of the transistor, we obtain:

$$P' = I_D' V_{DS} = \frac{1}{S^2} I_D V_{DS} = \frac{P}{S^2}$$

• With the device area reduction by S<sup>2</sup>, we find that the *power density* (W/cm<sup>2</sup>) remains unchanged for the scaled device

### Example of Typical CMOS Scaling

• Consider a more realistic scaling scenario where voltage is scaled down by S while all dimensions and doping densities are scaled up by M:

$$V_{new} = \frac{1}{S} V_{old} , \quad I_{new} = \frac{M}{S^2} I_{old} , \quad (C_L)_{new} = \frac{1}{M} (C_L)_{old}$$

$$freq_{new} = \frac{M^2}{S} freq_{old} , \quad power_{new} = \frac{M}{S^3} power_{old}$$

$$energy_{new} = \frac{1}{MS^2} energy_{old} , \quad pow\_dens_{new} = \frac{M^3}{S^3} pow\_dens_{old}$$

• With S<sup>-1</sup>=0.85 and M<sup>-1</sup>=0.7, we obtain:  $energy_{new} = 0.506 energy_{old}$ ,  $pow\_dens_{new} = 1.79 pow\_dens_{old}$ 



- However, the number of logic gates in a chip has been increasing by 3x per generation (since the die size is increasing correspondingly), thus a net increase in the energy consumption per chip
- The power density is increasing by about 80% per generation M. Pedram USC/EE



### Reality of CMOS Scaling

- Scaling increases:
  - Transistor density and functionality
  - Speed of operations
- V<sub>DD</sub> scaling is needed to maintain device reliability and reduce power dissipation
  - V<sub>T</sub> scaling needed to maintain switching speeds
  - $t_{ox}$  scaling needed to maintain the current drive and keep  $V_T$  variations under control when dealing with short-channel effects
- $V_T/V_{DD}$  is increasing with scaling
  - Effect of process variations on delay becomes higher
  - Delay sensitivity becomes intolerable when the  $V_T/V_{DD}$  ratio is at 0.5 or higher



Source: Taur

#### Fundamental Limits to CMOS Scaling

- Fundamental non-scaling effects are caused by the fact that neither the thermal voltage kT/q nor the silicon band gap changes with scaling
  - The first results in non-scaling of the subthreshold swing parameter
  - The latter results in non-scalability of built-in junction potential, depletion layer width, and short channel effects
- Maximum integration density is limited by the <u>power density</u> while maximum circuit speed is limited by the *parametric variability* 
  - Because of the field dependence of the carrier mobility, the gate speed will not improve linearly with scaling
  - There is adverse impact on device reliability due to high electric field stress



Source: Taur

### Physical Limits in Scaling Si MOSFET



### Power Dissipation and Temperature

- Power consumption and heat removal are limited by practical considerations:
  - Low power applications must be battery powered
  - Many must be light-weight  $\rightarrow$  power < ~few watts
  - Disposable batteries can cost >\$500/watt over the life of device
  - Rechargeables can cost > 50/watt over the life of device
- Home electronics is limited to < ~1000W due to heat generation in the rooms and the cost of electricity
- High performance is limited by difficulty of heat removal from chip (~100 W/chip) (Cost of electricity is ~\$5/watt over the life of device)
- Every 10°C increase on operating temperature double failure rate for the electronic components

### Components of Power Consumption

- The power consumption in CMOS digital circuits has three main components:
  - Capacitive (switching) power consumption
  - Short-circuit (rush-thru) power consumption
  - Leakage power consumption
- Chips with circuits other than conventional CMOS gates that have continuous current paths between the power supply and the ground, have an extra power component:

- Static (DC) power consumption

dynamic power consumption

#### Switching Power Consumption

- In digital CMOS circuits, switching power is dissipated when energy is drawn from the power supply to charge up the output node capacitance
- Total capacitive load at the output of a NOR gate consists of
  i) the output node cap. of the gate itself
  ii) the total interconnect cap.
  iii) the input cap. of the driven gates



A NOR gate driving two NAND gates through interconnection lines

# Derivation of Switching Power Consumption

• The average power dissipation can be calculated from the energy required to charge up the output node to  $V_{DD}$  and charge down the total output load capacitance to ground level.

#### Switching Power Consumption (Cont'd)

• Internal node voltage transitions can be partial, i.e., the node voltage swing may be only  $\Delta V_i$ , which is in general smaller than the full voltage swing of  $V_{DD}$ 

$$P_{avg} = \frac{1}{2} V_{DD} f_{CLK} \left( \sum_{i=1}^{\#of \ nodes} \beta_i \ C_i \ \Delta V_i \right)$$

where  $C_i$  = the parasitic capacitance associated with each node in the circuit  $\beta_i$  = the corresponding activity factor associated with the node

#### Short-Circuit Power Dissipation

- Let  $\tau_r = \tau_f = \tau$  denote the transition time of the input voltage,  $V_{in}$
- Now t<sub>1</sub> is the time when the input voltage reaches the threshold voltage of nMOS while t<sub>3</sub> is the time when the input voltage reaches the threshold voltage of pMOS
- The short-circuit current flows between  $t_1$  and  $t_3$  and reaches it maximum at  $t_2$  when  $V_{out} = V_{dd}/2$



#### Short Circuit Power Calculation

• Turgis et al model, which is based on the concept of an equivalent short circuit capacitance calculated under the assumption that the input and the <u>output</u> waveforms are <u>linear</u>, is as follows:

$$I_{sc}(\text{rising input}) = \frac{1}{6} k_{p} \tau_{in,r} V_{DD}^{2} \left( 1 - \frac{V_{T,n} + |V_{T,p}|}{V_{DD}} \right)^{2} \left( \frac{\tau_{in,r}}{\tau_{in,r} + \tau_{out,f}} \right) f_{CLK}$$

$$C_{sc} = \frac{I_{sc}T}{V_{DD}} = \frac{1}{6} k_{p} \tau_{in,r} V_{DD} \left( 1 - \frac{V_{T,n} + |V_{T,p}|}{V_{DD}} \right)^{2} \left( \frac{\tau_{in,r}}{\tau_{in,r} + \tau_{out,f}} \right)$$

$$P_{sc}(\text{rising input}) = \frac{1}{2} C_{sc} V_{DD}^{2} f_{CLK} = \frac{1}{12} k_{p} \tau_{in,r} V_{DD}^{3} \left( 1 - \frac{V_{T,n} + |V_{T,p}|}{V_{DD}} \right)^{2} \left( \frac{\tau_{in,r}}{\tau_{in,r} + \tau_{out,f}} \right) f_{CLK}$$

• For a symmetric CMOS inverter with  $k_n = k_p = k$ ,  $V_{T,n} = |V_{T,p}| = V_T$ , and equal input rise and fall times, the above equation becomes:

$$P_{sc} = \frac{1}{12} k \tau_{in} V_{DD} \left( V_{DD} - 2V_T \right)^2 \left( \frac{1}{1 + \tau_{out} / \tau_{in}} \right) f_{CLK} \beta$$

which almost reduces to Veendrick's result for  $\tau_{out}/\tau_{in} = 1$ 

### Regression-based Short Circuit Power Equation



$$P_{sc}(\tau_{in},k,C_{out}) \propto \frac{k \tau_{in}}{C_{out}} V_{DD} f_{CLK} \beta$$

### Dynamic Power Minimization Techniques

- Power management
  - Dynamic voltage and frequency scaling
  - Multiple voltage islands
- Trading area or latency for power
  - Pipelining
  - Parallelization
- Glitch suppression
- Clock gating
- Driving buses
  - Bus encoding
  - Low Swing buses and split buses
- Adiabatic circuits, stepwise charging, charge recycling

#### Reverse-Biased Junction Leakage

- Consider a CMOS inverter with a high input voltage
  - Although pMOS transistor is turned off, there will be a reverse potential difference of  $V_{DD}$  between its drain and the n-well



### Reverse-Biased Junction Leakage (Cont'd)

• The reverse leakage current of a pn-junction is expressed by

$$I_{reverse} = A \cdot J_s \cdot (1 - e^{-\frac{V_{RB}}{n \cdot \theta_T}})$$

$$I_{reverse} = A \cdot J_s \cdot (1 - e^{-\frac{W_{RB}}{n \cdot \theta_T}})$$

$$I_{reverse} = \int_{reverse}^{n \cdot region (drain of nMOS)} \int_{reverse}^{n \cdot region (drain of nMOS)} \int_{reverse}^{n \cdot region (bulk of nMOS)} \int_{reverse}^{n \cdot reverse} \int_{reverse}^{n \cdot rev$$

- A : the junction area
- $J_s$ : the maximum reverse saturation current density (typically 1-5 pA/ $\mu$ m<sup>2</sup>)
- *n* : the *emission coefficient*, usually set to 1, although can be larger depending on the type of junction
- $V_{RB}$ : the *reverse bias voltage* across the junction, i.e., the voltage of drain diffusion with respect to the bulk or well
- $-v_T = kT/q$  denotes the thermal voltage at absolute junction temperature, T
- $I_{reverse}$  is maximum when  $V_{RB}$  is largest, that is why we focus on the drain side and not the source side of the nMOS transistor
### Subthreshold Conduction Leakage

• Another component of leakage current is the subthreshold current, which is due to carrier diffusion between the source and the drain regions of the transistor in weak inversion



• The subthreshold leakage current can occur even when there is no switching activity in the circuit

$$I_{subthreshold} \cong \mu_0 C_{ox} \frac{W}{L} \mathcal{Q}_T^2(n-1) e^{\frac{V_{GS} - V_T + \eta V_{DS}}{n \mathcal{Q}_T}}$$

M. Pedram USC/EE

#### Gate Leakage

- With the advent of deep-submicron devices comes the reduction of the gateoxide thickness. This reduction leads to a higher electric field across the oxide
  - The tunneling of electrons through the gate oxide into the substrate and from substrate to the gate becomes possible. This current is referred to as gate leakage
  - Being quantum mechanical in nature, the gate leakage current is virtually temperature-independent  $(U_{1})^{2} \propto \frac{t_{ox}}{t_{ox}}$

$$I_{gate} \cong \kappa WL \left(\frac{V_{GB}}{t_{ox}}\right)^2 e^{-\alpha \frac{t_{ox}}{V_{GB}}}$$

where  $\kappa$  and  $\alpha$  are fitting parameters, W is the transistor width,  $V_{GB}$  denotes the gate to bulk voltage, and  $t_{ox}$  denotes the gate oxide thickness



### Total Power Dissipation in CMOS VLSI Circuits

• The total power dissipation is the sum of two components: dynamic (switching plus short-circuit) and leakage (reverse biased junction, subthreshold and gate currents)

$$\begin{split} P_{total} = & \frac{1}{2} \Biggl( C_{load} V_{DD} + \frac{k \tau_{in}}{6 \Biggl( 1 + \frac{\tau_{out}}{\tau_{in}} \Biggr) } \Bigl( V_{DD} - 2V_T \Bigr)^2 \Biggr) V_{DD} f_{CLK} \beta + V_{DD} I_{leakage} \\ & I_{leakage} = I_{reverse} + I_{subthreshold} + I_{gate} \end{split}$$

#### Example

Calculate the capacitive, short circuit, and leakage components of power dissipation of a CMOS inverter with  $W_p/L=2W_n/L=8$ , driving an identical inverter with the following parameters:  $\mu_{\rm n} = 2\mu_{\rm p} = 600 {\rm cm}^2 {\rm /V}{\rm -sec},$  $C_{\rm or} = 2 \times 10^{-7} \, {\rm F/cm^2},$  $V_{T,n} = -V_{T,p} = 0.6 \text{V}, V_{DD} = 2.8 \text{V},$  $t_{in}$ =100ps,  $t_{out}$ =300ps, activity factor  $\beta = 0.2$ ,  $f_{CLK} = 500$ MHz, die Temperature T=85 °C, the subthreshold shape parameter, *n* =1.5, Boltzmann constant, k= $1.38 \times 10^{-23}$  J/K, electron/hole charge,  $q=1.6 \times 10^{-19}$  C, and *L*=0.25µm.

$$\begin{aligned} k'_{n} &= \mu_{n}C_{ox} = 2k'_{p} = 2\left(\mu_{p}C_{ox}\right) = \left(600\frac{cm^{2}}{V\cdot s}\right) \left(2\times10^{-7}\frac{F}{cm^{2}}\right) = 120\frac{\mu A}{V^{2}} \\ k_{n} &= k_{p} = \mu_{n}C_{ox}\frac{W_{n}}{L} = \mu_{p}C_{ox}\frac{W_{p}}{L} = \left(120\frac{\mu A}{V^{2}}\right) (4) = \left(60\frac{\mu A}{V^{2}}\right) (8) = 480\frac{\mu A}{V^{2}} \\ C_{load} &= \left(W_{n} + W_{p}\right)LC_{ox} = 3W_{n}LC_{ox} = \frac{3}{2}W_{p}LC_{ox} = (12\times10^{-4}cm)(2\times10^{-4}cm)\left(2\times10^{-7}\frac{F}{cm^{2}}\right) = 48fF \\ \vartheta_{T} &= 1.38\times10^{-23}\frac{273+85}{1.6\times10^{-19}} = 308.8\times10^{-4}V = 30.9mV \\ \text{Note that since inverter is driving identical load } : \mu_{n}C_{ox}\frac{W_{n}}{L} = \mu_{n}\frac{C_{load}}{3L^{2}} = \left(2\mu_{p}\right)\frac{C_{load}}{3L^{2}} = \mu_{p}C_{ox}\frac{W_{p}}{L} \\ P_{total} &= \frac{1}{2}C_{load}V_{DD}^{-2}f_{CLK}\beta + \frac{k_{n}\tau_{m}}{12\left(1+\frac{\tau_{out}}{\tau_{m}}\right)}\left(V_{DD} - 2V_{T}\right)^{2}V_{DD}f_{CLK}\beta + \frac{\mu_{n}C_{load}}{3L^{2}} = \vartheta_{r}^{2}(n-1)e^{\frac{-V_{r}}{n\theta_{r}}}V_{DD} \\ P_{total} &= \frac{1}{2}(48f)(2.8V)^{2}(500MHz)(0.2) \\ &+ \frac{\left(480\frac{\mu A}{V^{2}}\right)(100\,ps)}{12\left(1+\frac{300}{100}\right)}\left(2.8V - 2\times0.6V\right)^{2}(2.8V)(500MHz)(0.2) \\ &+ \frac{\left(600\frac{cm^{2}}{V\cdot s}\right)\left(48fF\right)}{3(0.25\times10^{-4}cm)^{2}}\left(0.0309V\right)^{2}(0.5)e^{\frac{-06}{1.5\times00309}}(2.8V) \\ &= 18.816\muW + 0.717\muW + 0.863nW \end{aligned}$$

M. Pedram USC/EE

#### Example (Cont'd)

Consider a case in which the circuit is in busy state consuming capacitive and shortcircuit power for time  $T_{busy}$  and then remains idle for a time  $T_{idle}$ during which only leakage power is dissipated. Let's define the *duty factor* as  $\psi = T_{busy}$  /  $(T_{busy} + T_{idle})$ . Calculate the minimum value of  $\psi$  such that the idle state energy dissipation is no more than 10<sup>-3</sup> times the total energy dissipation of the CMOS inverter.

$$\begin{split} \psi &= \frac{T_{busy}}{T_{busy} + T_{idle}} = \frac{1}{1 + \frac{T_{idle}}{T_{busy}}} \\ E_{idle} &\leq 10^{-3} \times E_{tot} \\ 10^3 \times P_{leak} \times T_{idle} &\leq (P_{cap} + P_{sc}) \times T_{busy} + P_{leak} \times T_{idle} \\ \frac{T_{idle}}{T_{busy}} &\leq \frac{P_{cap} + P_{sc}}{999 \times P_{leak}} = \frac{18.816 \,\mu W + 0.717 \,\mu W}{999 \times 0.863 \,n W} = \frac{19.533 \,\mu W}{862.137 \,n W} = 22.66 \\ \psi &\geq \frac{1}{1 + 22.66} \approx 0.0423 \end{split}$$

### Effects due to High Die Temperatures

- Thermal effects are an inseparable aspect of electrical power generation and signal transmission
  - They arise from the substrate power generation and self-heating in the interconnects
- High temperature reduces the interconnect performance due to increase in electrical resistance and lowers the mean time to failure (MTTF) of VLSI interconnections due to more severe Electro-migration effect
  - Every 10 degrees Celsius increase in the die temperature increases wire delays by 5% and reduces the MTTF by 50%
- They are expected to become more severe due to CMOS technology scaling

#### Electrical-Thermal Analogy

- Analogous quantities
  - Electrical potential,  $V(Volt) \Leftrightarrow$  Temperature, T(Kelvin)
  - Charge, Q (Coulomb)  $\Leftrightarrow$  Heat, q (Joule)
  - Current, I (Ampere)  $\Leftrightarrow$  Heat flux = power, P=dq/dt, (*Watt*)
  - Electrical resistance, R (V/I= $\Omega$ )  $\Leftrightarrow$  Thermal resistance,  $R_T$  (K/W)
  - Electrical capacitance,  $C(C/V=F) \Leftrightarrow$  Thermal capacitance,  $C_T(J/K)$

$$\frac{\partial^2 V}{\partial z^2} = RC \frac{\partial V}{\partial t} \leftrightarrow \frac{\partial^2 T}{\partial z^2} = R_T C_T \frac{\partial T}{\partial t}$$

• Analogous laws

$$V = RI \leftrightarrow T = R_T P$$
$$I = C \frac{\partial V}{\partial t} \leftrightarrow P = C_T \frac{\partial T}{\partial t}$$

### Die Temperature Calculation

• 1-D heat conduction model

$$T_{Die} = T_a + R_T \left(\frac{P}{A}\right)$$

- $T_{Die} = 120 \ ^{\circ}\text{C} \ (180 \text{ nm})$
- $R_T = 1.07 \text{ cm}^2 \text{ °C/W}$
- For given packaging and cooling technologies (*R<sub>T</sub>*), the die temperature (*T<sub>die</sub>*) can be calculated for any ambient temperature (*T<sub>a</sub>*) and any technology node (*P* and *A*)
- Note that maximum temperature occurs in uppermost metal lines



#### Example of Die Temperature Profile

• Thermal map of a 9mm by 9mm ASIC chip – Su, ISLPED 2003



### $V_{\rm T}$ Dependence on Temperature

• Assuming that  $\Phi_{GC}$  and  $qN_{ox}$  remains unchanged with temperature and that  $n_i \propto T^{1.5}$ , we have:

$$\begin{split} V_T &= \left( \Phi_{GC} - \frac{qN_{OX}}{C_{OX}} + \frac{qN_I}{C_{OX}} \right) + \left( 2\frac{kT}{q}\ln(\frac{N_A}{n_i}) + \frac{\sqrt{2qN_A\varepsilon_{S_i}\left(\frac{kT}{q}\ln(\frac{N_A}{n_i}) + V_{SB}\right)}}{C_{OX}} \right) \\ &= A + BT\ln(\frac{\kappa}{T^{1.5}}) + C\sqrt{T\ln(\frac{\kappa}{T^{1.5}})} \qquad A, B, C, D > 0, \text{Ignoring } V_{SB} \\ \frac{\partial V_T}{\partial T} &= B\left(\ln(\frac{\kappa_1}{T^{1.5}}) - \frac{3}{2}\right) + \frac{C\left(\ln(\frac{\kappa_1}{T^{1.5}}) - \frac{3}{2}\right)}{2\sqrt{T\ln(\frac{\kappa_1}{T^{1.5}})}} \\ \text{Hard to say, but we expect: } \frac{\partial V_T}{\partial T} < 0 \end{split}$$

•  $V_T$  decreases with Temperature, i.e., the gate overdrive voltage,  $V_{GS}$ - $V_T$ , goes up at higher temperatures

#### Mobility Dependence on Temperature

 $N_{\rm D} = 10^{14} {\rm cm}^{-3}$ 

 $\mu_n \,[\mathrm{cm}^2/(\mathrm{Vs})]$ 

Impurity

• For short channel devices, the surface electron mobility is expressed as follows ( $V_{SB}=0V$ ):

$$\mu_{n}(eff) = \frac{\mu_{n0}}{1 + \zeta (V_{GS} - V_{T})} \qquad \zeta \ge 0$$

$$\frac{\alpha T^{-1.5}}{1 + \zeta (V_{GS} - A - BT - C\sqrt{T})} = \frac{\alpha}{(1 + \zeta V_{GS} - \zeta A)T^{1.5} - \zeta CT^{2} - \zeta BT^{2.5}} \qquad \alpha \ge 0$$

$$\frac{\partial \mu_{n}}{\partial T} = \frac{-\alpha \left(\frac{3}{2}(1 + \zeta V_{GS} - \zeta A)T^{0.5} - 2\zeta CT - \frac{5}{2}\zeta BT^{1.5}\right)}{((1 + \zeta V_{GS} - \zeta A)T^{1.5} - \zeta CT^{2} - \zeta BT^{2.5})^{2}}$$
Hard to say, but we expect:  $\frac{\partial \mu_{n}}{\partial T} < 0$ 

• Carrier mobility degrades at higher temperatures

### Temperature Effect on the ON current $(I_{on})$

• We consider the  $I_D(sat)$  equation here:

$$I_{D}(sat) = \frac{\mu_{n}C_{ox}}{2} \frac{W}{L} (V_{GS} - V_{T})^{2} (1 + \lambda V_{DS}) \qquad \lambda \ge 0$$
  
$$\frac{\partial I_{D}}{\partial T} = A \left( (V_{GS} - V_{T})^{2} \frac{\partial \mu_{n}}{\partial T} - 2\mu_{n} (V_{GS} - V_{T}) \frac{\partial V_{T}}{\partial T} \right) (1 + \lambda V_{DS})$$
  
Hard to say, but we expect :  $\frac{\partial I_{D}}{\partial T} < 0$ 

- $I_{on}$  decreases with temperature
- Increase in gate overdrive is smaller compared to carrier mobility degradation when the temperature goes up. That is why the MOSFET drain current degrades when the temperature is increased from 25°C to 125°C
  - For a 65 nm node, the  $V_T$  of an nMOS decreases by about 40mV for this temperature rise range; the carrier mobility is cut in nearly half

#### Effect on the Off Current $(I_{off})$

$$\begin{split} I_{off} &= \frac{W}{L} \mu_e(n-1) C_{ox} \left(\frac{kT}{q}\right)^2 e^{\frac{q\left(-A-BT-C\sqrt{T}\right)}{nkT}} = \rho T^2 e^{-\beta T^{-1} - \chi - \eta T^{-0.5}} \qquad \rho, \beta, \chi, \eta > 0 \\ \frac{\partial I_{sub}}{\partial T} &= 2\rho T e^{-\beta T^{-1} - \chi - \eta T^{-0.5}} + \rho T^2 \left(\beta T^{-2} + \frac{\eta}{2} T^{-1.5}\right) e^{-\beta T^{-1} - \chi - \eta T^{-0.5}} \\ &= \rho \left(2T + \beta + \frac{\eta}{2} \sqrt{T}\right) e^{-\beta T^{-1} - \chi - \eta T^{-0.5}} > 0 \end{split}$$

- *I<sub>off</sub>* increases at higher temperatures
- The  $I_{on}$  to  $I_{off}$  ratio is significantly reduced with higher temperatures



### Summary

- CMOS scaling trends
- Power dissipation in CMOS logic gates and circuits
- Dynamic power minimization techniques
- Effect of temperature on  $I_{on}/I_{off}$  ratio
- Next we shall consider leakage power minimization techniques

# Minimizing Leakage Power in CMOS: Design Issues

Centre SI Summer School on Nanoelectronic Circuits and Tools

Massoud Pedram Dept. of Electrical Engineering University of Southern California

July 15, 2008

#### Power Density Trends



After Nowak, et al.

# Leakage Power Minimization Techniques

- Lowering and/or turning off  $V_{\text{DD}}$
- Gate length biasing ( $V_{th}$  roll-off effect)
- Transistor stacking
- Applying minimum leakage input vector in sleep mode
- Utilizing the dual-Vth devices (possibly combined with  $V_{th}$  roll-off effect)
  - Static approach: assigns low- $V_{th}$  to timing-critical logic cells, high- $V_{th}$  to other cells
  - Dynamic approach (a.k.a. power gating): requires a control signal (SLEEP signal) to turn off devices in the standby mode
- Body-biasing
  - Bias the body of NMOS (PMOS) device  $V_b < GND (V_b > V_{DD})$  in sleep mode

#### Effect of Supply Voltage Scaling



#### Impact of Gate Length Variation



# Gate Length Biasing

- Slightly increase (bias) the gate-length (line width) of devices
  - Slightly increases delay
  - Significantly reduces leakage
  - Bias only the non-critical devices
- Advantages:



- Reduces runtime leakage and leakage variability
- Can work in conjunction w/ V<sub>th</sub> assignment → Gives finer control over delay-leakage tradeoff
- Post-layout technique, no additional masks required
- 15-40% leakage and 30-60% leakage variability reduction for 90nm with dual- $V_{th}$  assignment [Source: Gupta et al]

#### Dual-Vt Design for Leakage Control



Source: De et al

#### **Optimal Vt Choices**



#### Example Dual Vt Optimization

- The following circuit is designed in 65nm CMOS technology using low threshold transistors. Each gate has a delay of 5ps and a leakage current of 10nA. Given that a gate with high threshold transistors has a delay of 12ps and leakage of 1nA, optimally design the circuit with dual-threshold gates to minimize the leakage current without increasing the critical path delay.
  - (a) What is the percentage reduction in leakage power?
  - (b) What will the leakage power reduction be if a 30% increase in the critical path delay is allowed?



#### Dual Vt Example (Cont'd)

Part (a): Three critical paths are from the ٠ first, second and third inputs to the last output, shown by a dashed line arrow. Each has five gates and a delay of 25ps. None of the five gates on the critical path (red arrow) can be assigned a high threshold. Also, the two inverters that are on four-gate long paths cannot be assigned high threshold because then the delay of those paths will become 27ps. The remaining three inverters and the NOR gate can be assigned high threshold. These gates are shaded grey in the circuit. The reduction in leakage power =  $1 - (4 \times 1 + 7 \times 10)/(11 \times 10) =$ 32.73%.



• Critical path delay = 25ps

#### Dual Vt Example (Cont'd)

- Part (b): Several solutions are possible. Notice that any 3-gate path can have 2 high threshold gates. Four and five gate paths can have only one high threshold gate. One solution is shown in the figure below where six high threshold gates are shown with shading and the critical path is shown by a dashed red line arrow. The reduction in leakage power = 1 – (6×1+5×10)/(11×10) = 49.09%.
- Critical path delay = 29ps



#### Leakage Current of Transistor Stacks



Source: De-2004

#### **Exploiting Natural Stacks**



Reduction	Avg	Worst
High V <sub>T</sub>	1.5X	2.5X
Low V <sub>T</sub>	1.5X	2X

Source: De-2004

#### Stack Forcing for Leakage Control



Low-Vt + stack-forcing reduces leakage power by 3X

# Input Dependence of the Leakage Current



Technology: 0.18 μm Supply Voltage = 1.5V Threshold Voltage = 0.2V



$X_0 X_1$	Leakage
0 0	23.60 nA
0 1	47.15 nA
1 0	51.42 nA
1 1	82.94 nA

# Input Vector Control During Sleep Mode



M. Pedram USC/EE

### Multi-Threshold CMOS

- High- $V_{th}$  power switches are connected to low- $V_{th}$  logic gates
  - Achieves high performance due to low-V<sub>th</sub> logic gates
  - Reduces leakage power dramatically due to the series-connected high-V<sub>th</sub> power switch
- Typically only a header or a footer sleep transistor is used, not both
- A single sleep transistor may be shared among several logic gates



#### Footer Gate Width Selection

#### A 2-stage pipelined 40-bit ALU (IBM)



#### Sleep Transistor Sizing Example

Consider the following MTCMOS inverter. Assuming zero effective resistance, R<sub>DS,ON</sub>, for the sleep transistor, M<sub>sleep</sub>, calculate, I<sub>active</sub>, the peak value of the current that discharges the load capacitance in a high to low transition at the output?
 Solution: This is the value of the current through transistor M2 immediately after *In* switches from 0 to V<sub>DD</sub>. M2 is in the saturation region:

$$I_{active} = I_{DS,M2} = 57.5 \mu \times 2.5 \times (2.3)^2 = 760 \mu A$$



#### Sleep Transistor Sizing

• Suppose that the maximum delay penalty of the MTCMOS circuit compared to the original CMOS inverter is 5%. Calculate the max value of  $V_x$  to ensure this timing requirement.

$$\frac{\tau_{d,SLEEP}}{\tau_d} = \frac{(V_{DD} - V_{tnl})^2}{(V_{DD} - V_X - V_{tnl})^2} = 1.05, \quad \frac{V_{DD} - V_{tnl}}{V_{DD} - V_X - V_{tnl}} = 1.025$$

$$V_X = \frac{0.025 \times (V_{DD} - V_{tnl,0})}{1.025} = \frac{0.025 \times 2.3}{1.025} = 0.0561V$$

$$V_{tnl} \left( V_{SB} = 0.056 \right) = V_{T0} + \gamma \left( \sqrt{|2\phi_F| + V_{SB}} - \sqrt{|2\phi_F|} \right) = 0.2 + 0.8 \left( \sqrt{0.6 + 0.0561} - \sqrt{0.6} \right) = 0.228$$

$$V_X = \frac{0.025 \times (V_{DD} - V_{tnl,0})}{1.025} = \frac{0.025 \times 2.272}{1.025} = 0.0554V$$

• Using  $I_{active}$  and  $V_x$ , find the minimum size of the sleep transistor,  $(W/L)_{sleep}$ . We write the current equation through the sleep transistor when its  $V_{DS}$  is equal to  $V_x$  obtained above and set this current equal to  $I_{active}$ .

$$I_{sleep} = 115 \frac{\mu A}{V^2} \times \left(\frac{W}{L}\right)_{sleep} \times \left((V_{DD} - V_{th,sleep})V_x - \frac{V_x^2}{2}\right) = I_{active}$$
$$115 \times \left(\frac{W}{L}\right)_{sleep} \times \left(2 \times 0.056 - \frac{(0.056)^2}{2}\right) = 760, \quad \left(\frac{W}{L}\right)_{sleep} = 60$$

M. Pedram USC/EE

#### Header vs. Footer Switches



- Area and power dissipation overhead of NMOS footer transistors are lower due to higher mobility of electrons
- PMOS header transistors are more compatible with two-well bulk CMOS process where a high-performance NMOS transistor realized in the substrate is desirable



Triple well structure provides an isolating N layer between the local P-well and the P-substrate.

## Coarse-Grain vs. Fine-grain MTCMOS

- Merits of fine-grain MTCMOS
  - Easier to incorporate into existing EDA flows and tools
  - Less parasitics on the virtual node and less EM problems

- Merits of coarse-grain MTCMOS
  - Smaller sleep transistor area and mode transition power overheads
  - Lower leakage due to smaller sleep transistor width


# Sleep Transistor Layouts for Internal Switches





Single transistor footer switch

Single transistor header switch



Double-transistor (mother/daughter) footer switch

#### Layout Styles for Internal Footer Switch



Sleep Signal Scheduling for Two Parallel Sleep Transistors

- There is a large current rush in sleep to active transition which can cause EM and IR-drop issues
  - Rush current can be reduced by using parallel (mother-daughter) sleep transistors
  - Total sleep transistor width, the summation of the SLEEPB1 mother and daughter switch widths, is determined by using a sizing algorithm
     SLEEPB2
- The peak rush current and IR drop across the switch can be controlled by optimizing the ratio of the daughter and mother transistor widths and scheduling the turn-on times of the two switches so as to minimize the wakeup delay



#### Staircase Sleep Scheduling

- Reduce ground bounce by turning on the sleep transistor in two steps:
  - First use a weak PMOS:  $V_{gs} < V_{dd}$  for the sleep transistor. Originally,  $V_{ds}$  is high. So, the peak current is controlled
  - Next use a strong PMOS:  $V_{gs} = V_{dd}$  for the sleep transistor.  $V_{ds}$  is however low. Therefore, the peak current is reduced



### Parallel Sleep Transistors

• Alternatively, one may use several sleep transistors

Successively turn them on with cycle delays

 The resistance between the virtual ground and the ground is reduced as the V<sub>ds</sub> of the sleep transistor is lowered. This reduces the peak current



### Power Gating Example





#### Power Switch used in OMAP

90nm OMAP2420 SoC

- Five power domains in OMAP SoC enabled by power gating
- Power switches gate  $V_{DD}$ , consists of
  - Weak PMOS: Sinks low current for power restoration
  - Strong PMOS: Deliver current for normal operation
- 2-pass power turn-on mechanism to prevent current surges
  - Weak switches turned on first to almost fully restore  $V_{DD}$  (local), and then the strong switches are turned on to support normal operation



# Mode Transition Energy Minimization

- Energy consumption needed for mode transitions can be significant for power-gated circuits
  - A charge-recycling technique can be used to minimize the power consumption during the mode transition in an MTCMOS circuit while maintaining, or sometimes even improving, the wake up time
  - The charge recycling switch cell is turned on right before going from sleep to active and right after going from active to sleep



## Mode Transition Energy (cont'd)

- During the sleep mode, voltage values for VVSS and VVDD reach  $V_{\text{DD}}$  and 0, respectively
- The circuit is put to a half-wakeup state by turning the charge recycling circuitry on at the sleep-to-active transition edge and right before turning on the sleep transistors
- After charge recycling is complete, the charge recycling circuitry is turned off and the sleep transistors are turned on to completely wake up the circuit. A similar strategy is used during the active-sleep transition
- Total energy saving is:

$$ESR = \frac{2C_{VVSS}C_{VVDD}}{\left(C_{VVSS} + C_{VVDD}\right)^{2}}$$

• The maximum ESR of 50% is obtained when  $C_{VVSS} = C_{VVDD}$ 



# Local Sleep Signal Generation for Autonomous Power Gating

- A local sleep signal for each block can be generated which can automatically put the block into sleep independent of the global sleep signal
- A small circuitry may be added to compare the current input signals to the block with the input signals of the previous clock, and generate a local sleep signal when there is no change in the input signals for a given number of the clock cycles



# Voltage Rail Clamp (VRC) and Park Mode

- Voltage Rail Clamp: Reduce the virtual supply and ground voltages using two diodes
  - This allows state retention
  - It reduces noise during transition to active mode
  - However, the leakage saving in sleep mode is reduced
- Park Mode: Use a normally-on PMOS transistor to clamp virtual ground
  - Reduces leakage and bounce noise during wakeup
  - Keeps the internal state
  - Can turn off the PMOS transistor when in the sleep mode to achieve higher leakage saving. However, internal state will be lost





#### **MTCMOS** Fencing





• Store the data in a latch before disconnecting the module from the ground

#### State Retention



#### Data Processor with Power Gating Support



Sleep Req=1 $\rightarrow$  Stop Clk=1 $\rightarrow$ Sclk disabled $\rightarrow$ Sleep=1 $\rightarrow$ VDD Control=1 $\rightarrow$ VVDD floats

# State-Retentive Master-Slave Flip-Flop

(Freescale)



#### Power Management Example

- Consider a logic circuit that can be in one of two modes of operation: *Busy state* where it is doing useful work and *Idle state* where it is sitting idle waiting for workload to arrive. The circuit can be placed in one of two states: *Active mode* where the full  $V_{DD}$  level is applied to the circuit and a *Sleep mode* where the circuit is power gated using a high  $V_T$  sleep transistor. We assume the power dissipations in active and sleep modes are 1mW and 50µW, respectively.
- A power management controller counts the number of cycles that the circuit has been idle, and after 100 idle cycles, it will generate a control signal to a power-gating sleep transistor in order to transition the circuit into the sleep mode. The transitions into and out of the sleep mode take 10 cycles each, during which the circuit consumes <sup>1</sup>/<sub>4</sub> of the active power dissipation on average. For each of the two mode transitions, the energy dissipation by the driver of the sleep transistor is 1nJ.
- We calculate the minimum duration of the *sleep mode* (in number of cycles) for the transition from the active to sleep mode and back to active mode to result in energy saving compared to the case that the circuit is never put to sleep and stays in the active mode all the time (clock frequency is100MHz).

# Example (Cont'd)

#### • Solution:

Each clock cycle=10ns

Number of cycles in the transition from Active to sleep mode and back to active mode =  $100+10\times2=120$ 

Number of cycles in the sleep mode = x

Energy dissipation if the circuit was always in the active mode =  $(120+x)\times10ns\times1mW=(1.2+0.01 x)\times10^{-9}nJ$ 

Energy dissipation if the circuit is put to sleep and awakened =  $100 \times 10$ ns $\times 1$ mW+20 $\times 10$ ns $\times 0.25$ mW+1 $\times 2$ nJ+ $x \times 10$ ns $\times 0.050$ mW=(3.05+0.0 005x) $\times 10^{-9}$  nJ  $\rightarrow 1.2+0.01x=3.05+0.0005x \rightarrow 0.0095x=1.85 \rightarrow x=194.7$ 

The minimum number of cycles to be in the sleep mode=195.

# Supper Cut-Off CMOS (SCCMOS)

- MTCMOS uses high  $V_{th}$  as a cut-off MOSFET in series with low- $V_{th}$  logic circuits to cut-off leakage current in standby mode
- MTCMOS does not work below 0.6V supply voltage because the high-V<sub>th</sub> MOSFET does not turn on
  - MTCMOS cannot be used in sub-1-V
    V<sub>DD</sub>
- Super cut-off CMOS has been proposed to solve this problem
  - The cut-off device in SCCMOS is low- $V_{th}$  MOSFET, thus no need for high- $V_{th}$ MOSFET
  - The low- $V_{th}$  assures high speed operation



# SCCMOS

- Instead of increasing  $V_{th}$ , SCCMOS increase the  $|V_{GS}|$  value in the off region of the cut-off device
  - SCCMOS with a pMOS insertion case is shown below
- The low- $V_{th}$  cut-off pMOS, M1, is inserted in series to the logic circuit consisting of low- $V_{th}$  MOSFETs
- The gate voltage of M1,  $V_G$ , is grounded in active mode
- When the logic circuits enter standby operation, V+ is overdriven to  $V_{DD}$ +0.4 V to completely cut off the leakage current
- This is because the low- $V_{th}$  of 0.1–0.2 V is lower by 0.4 V than conventional high- $V_{th}$  (0.5–0.6 V), and thus this overdriven mechanism can sustain the standby current level



# Dynamic Body Biasing for Active Mode Leakage Control



M. Pedram USC/EE

#### Dynamic Sleep Transistor



#### Performance Impact

Body bias

#### Sleep transistor



Source: De-2004

#### Nwell Biasing in Two-Well Process



# Nwell and Pwell Biasing in Triple-Well Process



# Basic Guidelines for Power Minimization

- Do not do more than necessary
  - avoid wasteful power dissipation: clock gating
  - do not optimize for 'worst case' but for the 'current case': DVFS
  - react to the environment: DPM
  - use bus encoding, reduced swing signaling, etc.
- Use Locality of reference
  - store results locally
  - avoid communication over long distances
  - avoid off-chip communications (1000 times more expensive)
- Be energy aware at all levels of your system: technological, system architecture, operating system, applications
  - do the tasks at the most energy-efficient platform/way
  - match algorithm with architecture